

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 10/728,532
Confirmation No. 8286
Filing Date December 5, 2003
Inventor..... John F. Van Itallie et al.
Assignee..... Micron Technology, Inc.
Group Art Unit..... 1756
Examiner Kathleen Duda
Attorney's Docket No. MI22-2458
Customer No. 021567
Title: Photolithographic Methods Of Using A Single Reticle To Form Overlapping Patterns

RESPONSE TO JUNE 1, 2006 FINAL OFFICE ACTION

Response Filed After Final Action

To: Mail Stop AF
Commissioner for Patents
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AMENDMENTS